OIPES/N 09/834,751

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

licant: Sergey A. Velichko et al.

Examiner:

Craig Steven Miller

Sirial No.:

09/834,751

Group Art Unit:

2857

Filed:

April 13, 2001

Docket:

303.750US1

Title: CONCURRENT CONTROL OF SEMICONDUCTOR PARAMETRIC TESTING

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

MS Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

In compliance with the duty imposed by 37 C.F.R. § 1.56, and in accordance with 37 C.F.R. §§ 1.97 et. seq., the enclosed materials are brought to the attention of the Examiner for consideration in connection with the above-identified patent application. Applicants respectfully request that this Supplemental Information Disclosure Statement be entered and the documents listed on the attached Form 1449 be considered by the Examiner and made of record. Pursuant to the provisions of MPEP 609, Applicants request that a copy of the 1449 form, initialed as being considered by the Examiner, be returned to the Applicants with the next official communication.

Pursuant to 37 C.F.R. §1.97(c)(2), please charge the required the fee of \$180.00 as set forth in 37 C.F.R. §1.17(p) to Deposit Account No. 19-0743.

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Filing Date: April 13, 2001

Dkt: 303.750US1

Title: CONCURRENT CONTROL OF SEMICONDUCTOR PARAMETRIC TESTING

Pursuant to 37 C.F.R. 1.98(a)(2), Applicant believes that copies of cited U.S. Patents and Published Applications are no longer required to be provided to the Office. Notification of this change was provided in the United States Patent and Trademark Office OG Notices dated October 12, 2004. Thus, Applicant has not included copies of any US Patents or Published Applications cited with this submission. Should the Office require copies to be provided, Applicant respectfully requests that notice of such requirement be directed to Applicant's belowsigned representative. Applicant acknowledges the requirement to submit copies of foreign patent documents and non-patent literature in accordance with 37 C.F.R. 1.98(a)(2).

The Examiner is invited to contact the Applicants' Representative at the below-listed telephone number if there are any questions regarding this communication.

Respectfully submitted,

SERGEY A. VELICHKO ET AL.

By their Representatives,

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CERTIFICATE UNDER 37 CFR 1.8: The undersigned hereby certifies that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail, in an envelope addressed to: MS Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on this 4 day of September, 2005.

Name

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INFORMATION DISCLOSURE
TRADES ATEMENT BY APPLICANT Complete if Known 09/834,751 **Application Number** April 13, 2001 **Filing Date** (Use as many sheets as necessary) Velichko, Sergey **First Named Inventor Group Art Unit** 2857 Miller, Craig **Examiner Name** Attorney Docket No: 303.750US1 Sheet 1 of 1

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DATE CONSIDERED EXAMINER